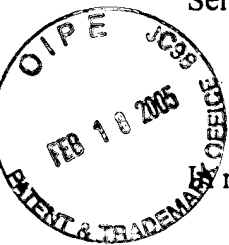


Serial No.: 10/689,506

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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Is re patent application of

Docket No. FIS920030241US

Huajie Chen

Serial No.: 10/689,506

Examiner: Munson, Gene M.

Filed: October 20, 2003

Art Unit: No. 2811

For: **HIGH PERFORMANCE STRESS-ENHANCED MOSFETS USING SI:C AND  
SIGE EPITAXIAL SOURCE/DRAIN AND METHOD OF MANUFACTURE**

U.S. Patent and Trademark Office  
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**RESPONSE TO RESTRICTION REQUIREMENT**

Sir:

In response to the Restriction Requirement dated January 21, 2005, Applicants elect Group II, claims 1-18, without traverse.

Applicants believe that no extensions of time or fees for net addition of claims are required at this time. However, if additional extensions of time are necessary to prevent abandonment of this application, then such extensions of time are hereby petitioned under 37 C.F.R. §1.136(a), and any fees required therefor (including fees for net addition of claims) are hereby authorized to be charged to International Business Machines Corporation's deposit Account No. 09-0458.